

<b>Search Notes</b>	<b>Application/Control No.</b>	<b>Applicant(s)/Patent Under Reexamination</b>
	10632499	OLSCHEWSKI, FRANK
	<b>Examiner</b>	<b>Art Unit</b>
	Dennis Rosario	2624

### SEARCHED

<b>Class</b>	<b>Subclass</b>	<b>Date</b>	<b>Examiner</b>
382	103	3/6/08	DR
348	169	3/6/08	DR
382	103 updated	9/2/08	DR
		3/24/09	DR
345	181	3/24/09	DR
348	169-172, 208.14	3/24/09	DR
359	383	3/24/09	DR
396	51	3/24/09	DR
382	107	10/2/2009	DR
382	103,107	5/20/2010	DR
244	3.1	5/20/2010	DR

### SEARCH NOTES

<b>Search Notes</b>	<b>Date</b>	<b>Examiner</b>
East, all dB	3/6/08	DR
ACM-+microscope +trajectory +vector-	3/6/08	DR
IEEE-(((microscope)<in>metadata)<and>((track*)<in>metadata))<and>((vector)<in>metadata))-	3/6/08	DR
East, all db, updated	9/2/08	DR
IEEE-((trajector* <near/5> pixel)<in>metadata)-	9/2/08	DR
East, all db	3/24/09	DR
Google Scholar-trajectory pixel vector field-	3/24/09	DR
East, all db	10/2/2009	DR
Google Scholar-displacement vector field microscope-	10/2/2009	DR
East, all db	5/20/2010	DR
Google Scholar-vector field trajectory-	5/20/2010	DR

### INTERFERENCE SEARCH

<b>Class</b>	<b>Subclass</b>	<b>Date</b>	<b>Examiner</b>